

Peter Kinnell

List of Publications by Year in descending order

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33
papers

356
citations

759055

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312
citing authors

#	ARTICLE	IF	CITATIONS
1	Pragmatic Micrometre to Millimetre Calibration Using Multiple Methods for Low-Coherence Interferometer in Embedded Metrology Applications. <i>Sensors</i> , 2021, 21, 5101.	2.1	3
2	A Data-Driven Method for Predicting Deformation of Machined Parts Using Sparse Monitored Deformation Data. <i>Advances in Transdisciplinary Engineering</i> , 2021, , .	0.1	0
3	Special Issue on Manufacturing Metrology. <i>Applied Sciences (Switzerland)</i> , 2021, 11, 10660.	1.3	1
4	Performance Evaluation of a Robot-Mounted Interferometer for an Industrial Environment. <i>Sensors</i> , 2020, 20, 257.	2.1	1
5	Virtual Reality Study of Human Adaptability in Industrial Human-Robot Collaboration. , 2020, , .		7
6	From Light to Displacement: A Design Framework for Optimising Spectral-Domain Low-Coherence Interferometric Sensors for In Situ Measurement. <i>Applied Sciences (Switzerland)</i> , 2020, 10, 8590.	1.3	6
7	Detecting Changes and Avoiding Catastrophic Forgetting in Dynamic Partially Observable Environments. <i>Frontiers in Neurorobotics</i> , 2020, 14, 578675.	1.6	2
8	Inspecting manufacturing precision of 3D printed concrete parts based on geometric dimensioning and tolerancing. <i>Automation in Construction</i> , 2020, 117, 103233.	4.8	22
9	Lensless fiber-deployed low-coherence interferometer for in-situ measurements in nonideal environments. <i>Optical Engineering</i> , 2020, 59, 1.	0.5	6
10	Establishing the performance of low-cost Lytro cameras for 3D coordinate geometry measurements. <i>Machine Vision and Applications</i> , 2019, 30, 615-627.	1.7	2
11	Abnormality detection strategies for surface inspection using robot mounted laser scanners. <i>Mechatronics</i> , 2018, 51, 59-74.	2.0	18
12	Novel metrics and methodology for the characterisation of 3D imaging systems. <i>Optics and Lasers in Engineering</i> , 2017, 91, 169-177.	2.0	9
13	Autonomous metrology for robot mounted 3D vision systems. <i>CIRP Annals - Manufacturing Technology</i> , 2017, 66, 483-486.	1.7	18
14	Plastic Deformation of Micromachined Silicon Diaphragms with a Sealed Cavity at High Temperatures. <i>Sensors</i> , 2016, 16, 204.	2.1	16
15	Performance Assessment of a New Variable Stiffness Probing System for Micro-CMMs. <i>Sensors</i> , 2016, 16, 492.	2.1	19
16	Variable stiffness probing systems for micro-coordinate measuring machines. <i>Precision Engineering</i> , 2016, 43, 262-269.	1.8	13
17	Characterizing the influence of surface roughness and inclination on 3D vision sensor performance. , 2015, , .		3
18	The suitability of lightfield camera depth maps for coordinate measurement applications. <i>Proceedings of SPIE</i> , 2015, , .	0.8	2

#	ARTICLE	IF	CITATIONS
19	High precision self-alignment using liquid surface tension for additively manufactured micro components. Precision Engineering, 2015, 40, 230-240.	1.8	6
20	Fabrication and characterisation of a novel smart suspension for micro-CMM probes. Sensors and Actuators A: Physical, 2015, 232, 368-375.	2.0	9
21	Soluble Abrasives for Waterjet Machining. Materials and Manufacturing Processes, 2014, 29, 1346-1352.	2.7	23
22	Fabrication of a Smart Suspension Structure of Micro Tactile Probing. Procedia Engineering, 2014, 87, 1164-1167.	1.2	3
23	Surface finishing of intricate metal mould structures by large-area electron beam irradiation. Precision Engineering, 2013, 37, 443-450.	1.8	48
24	The Unpredictable Errors of Micro Tactile Metrology – Factors Affecting Stylus tip Contamination. Measurement Science Review, 2013, 13, 305-310.	0.6	2
25	Rapid Manufacturing of Micro Devices with Integral Electrical Tracks. Procedia Engineering, 2012, 47, 734-737.	1.2	2
26	Evaluation Tip Cleaning for a Micro CMM Touch Trigger Stylus Sensor. Procedia Engineering, 2012, 47, 306-309.	1.2	5
27	A hollow stiffening structure for low-pressure sensors. Sensors and Actuators A: Physical, 2010, 160, 35-41.	2.0	27
28	The creep behaviour of the microfabricated silicon diaphragms at 900°C. Microelectronic Engineering, 2010, 87, 1213-1216.	1.1	6
29	Advances in Silicon Resonant Pressure Transducers. Procedia Chemistry, 2009, 1, 104-107.	0.7	40
30	A Hollow Stiffening Structure for Low Pressure Sensors. Procedia Chemistry, 2009, 1, 100-103.	0.7	0
31	Characterization of a micro-engineered selective strain-coupling structure using Raman spectroscopy. Journal of Micromechanics and Microengineering, 2005, 15, 807-811.	1.5	3
32	Physical characterisation of selective stress coupling for resonant pressure sensors. Sensors and Actuators A: Physical, 2004, 115, 230-234.	2.0	14
33	A dry single-step process for the manufacture of released MEMS structures. Journal of Micromechanics and Microengineering, 2003, 13, 790-794.	1.5	20